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Note on Printing

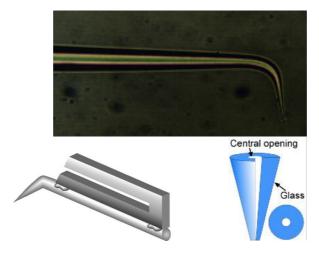
This manual is designed to be printed in color, single-sided on A4 paper

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<u>AFM based Nanolithography</u> <u>General Information:</u>

AFM based Nanolithography can achieve sub-micron nano-writing of a variety of materials with a highly controlled spatial accuracy. Glass hollow capillary is pulled to create a nanopipette with a tiny aperture (could be as small as a few tens of nanometers). The nanopipette is glued on a tuning fork; hence it could be controlled by the AFM system and be accurately positioned on the substrate.



The Nanolithography mechanism is based on capillary forces that are created between the liquid inside the nanopipette opening and the substrate. Hence this method is often referred to as **Fountain-pen-Nanolithography** or **FPN** method.

Nanonics recent innovation is the use of electrically driven flow to create highly controlled material patterns along with the highly controlled positioning of the nanopipette. The electrical field that is applied across the nanopipette could enhance or disable the flow of the material from the nanopipette, hence giving another dimension of control over the written pattern. Voltage applied across a glass nanopipette could create electroosmotic or even electrophoretic flows. Dielectrophoresis could be achieved in some configurations. These are research fields and in this manual we will only try to give you the tools to allow you to carry out research in these fields, along with giving you a tool for more controlled Nanolithography method and a method for liquid nano-injection.

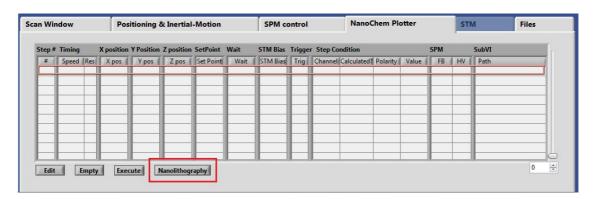
Nanolithography Software

Software Activation

- 1. In order to activate Nanolithography Add-On Software click on *Software* tab in NWS software and then click on *Unlock Features* button.
- 2. Put the activation code [56674] in "NanoPlot" field and click Ok button. The *Nanochem Plotter* tab will be activated.

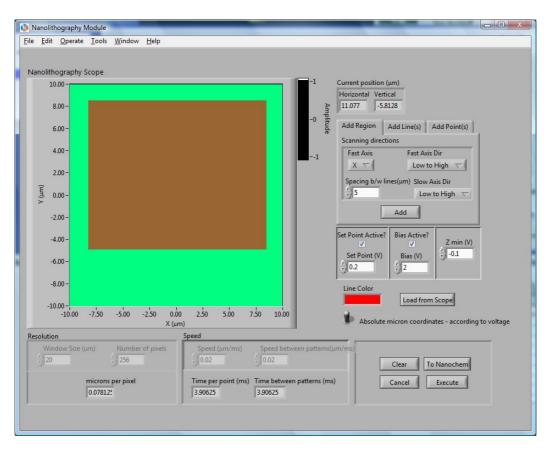


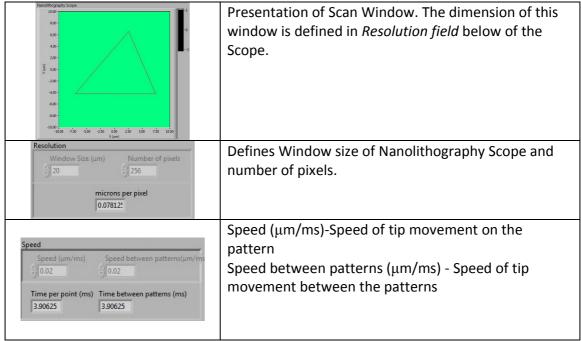
3. Click on NanoChem Plotter tab and then click on *Nanolithography* button to open the Add-On software.

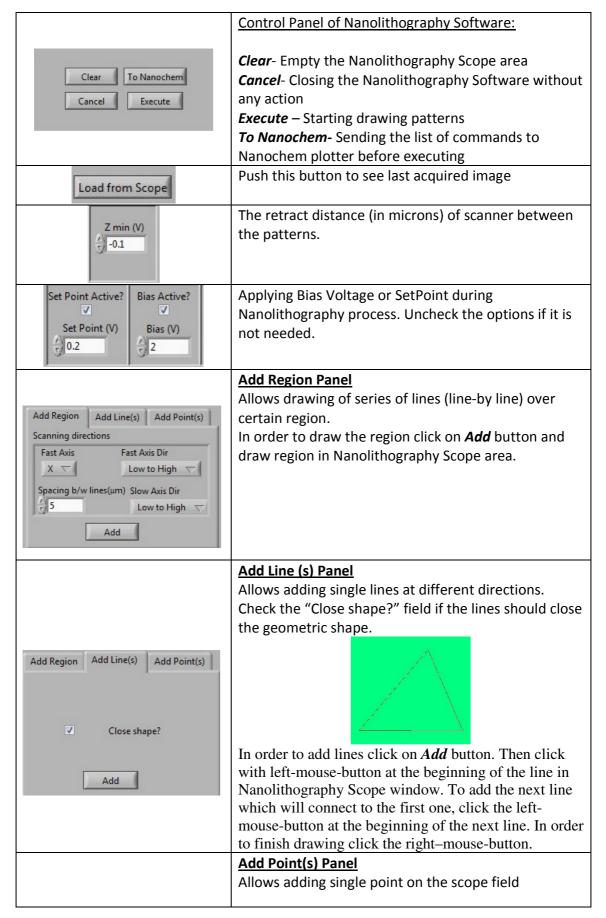


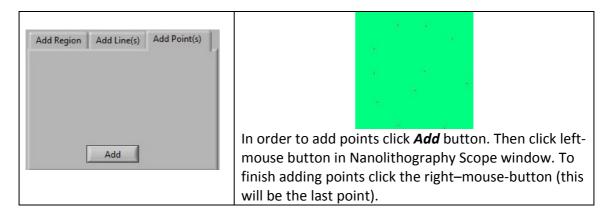
Software description

The main window of Nanolithography Software is represented below.

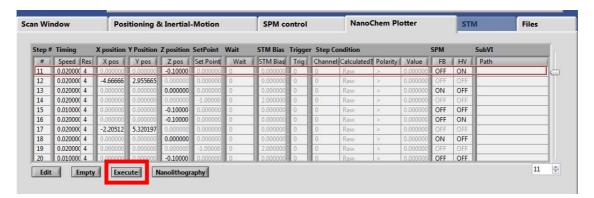








4. In order to see the list of commands click on "To Nanochem" button. The list of commands will appear in the table.



- 5. Click Execute to start drawing the patterns.
- 6. In order to empty the table click on *Empty* button